## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Hiroyuki KANBARA et al.

Application No.: 10/596,000

Confirmation No.: 1561

Filing or 371(c) Date: January 17, 2007

Title: METHOD FOR FORMING THICK FILM

PATTERN, METHOD FOR

MANUFACTURING ELECTRONIC

COMPONENT, AND PHOTOLITHOGRAPHY PHOTOSENSITIVE PASTE Art Unit: 1795

Examiner: A. Eoff

## REQUEST FOR RECONSIDERATION

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In response to the Office Action dated December 22, 2009, please reconsider the above-identified application in view of the following remarks.

**Listing of the Claims** begins on page **2**. No amendments have been made to the Claims.

Remarks/Arguments begin on page 6 of this paper.